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TECHNICAL SPECIFICATION

Nanomanufacturing - Key control characteristics -
Part 6-26: Graphene-related products - Fracture strain and stress, Young's modulus, residual strain and residual stress: bulge test

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INTERNATIONAL ELECTROTECHNICAL COMMISSION

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Full information on the voting for its approval can be found in the report on voting indicated in the above table.

The language used for the development of this Technical Specification is English.